

Listing of the claims:

Claims 1-52 are withdrawn from consideration.

1 53. (Original) A method for making an optical switching component comprising:

2 providing a substrate;

3 forming a stator by defining a cavity within the substrate;

4 forming a mask layer over the stator and filling the cavity;

5 forming an opening in the mask layer;

6 forming within the opening a rotor and a pivotal connection to the stator;

7 removing the mask layer; and

8 forming a piezoelectric actuator between the stator and the rotor.

1 54. (Original) The method of claim 53 wherein the substrate includes silicon.

1 55. (Original) The method of claim 53 wherein defining a cavity is performed by

2 photolithography.

1 56. (Original) The method of claim 53 wherein the mask layer includes photoresist.

1 57. (Original) The method of claim 53 wherein forming an opening is performed by

2 photolithography.

1 58. (Original) The method of claim 53 wherein removing the mask layer is performed by

2 wet chemical etching.

1 59. (Original) The method of claim 53 wherein forming a piezoelectric actuator is
2 performed before forming a rotor.

1 60. (Original) The method of claim 59 wherein forming a piezoelectric actuator is
2 performed by a deposition process.

1 61. (Original) The method of claim 53 wherein forming a piezoelectric actuator is
2 performed by a mechanical process.

1 62. (New) The method of claim 53, further including forming an optically reflective
2 surface on the rotor.

1 63. (New) The method of claim 53, wherein forming the piezoelectric actuator includes
2 manufacturing the piezoelectric actuator separately and inserting the piezoelectric
3 actuator between the stator and the rotor.

1 64. (New) The method of claim 53, wherein forming the piezoelectric actuator occurs
2 prior to removing the mask layer.

1 65. (New) A method for making an optical switching component comprising:
2 providing a substrate;
3 forming a stator from the substrate by defining a cavity within the substrate;
4 forming a mask layer over the stator, the mask layer filling the cavity;
5 forming an opening in the mask layer;

- 6 forming within the opening a rotor and a pivotal connection between the rotor and
- 7 the stator;
- 8 removing the mask layer; and
- 9 forming a piezoelectric actuator between the stator and the rotor.